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4/24/03  
Atty. Docket No. 1501-1147

PATENTS

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of

L. Karsten V. LINDSTRÖM et al.

Confirmation No. 5262

Serial No. 09/924,605

GROUP 1765

Filed August 9, 2001

Examiner Lan Vinh

A METHOD TO OBTAIN CONTAMINATION  
FREE LASER MIRRORS AND PASSIVATION  
OF THESE

AMENDMENT

Commissioner for Patents

Washington, D.C. 20231

Sir:

Responsive to the Official Action of October 23, 2002,  
please amend the above-identified application as follows:

IN THE SPECIFICATION:

Page 9, replace the paragraph beginning on line 42 and  
bridging pages 9 and 10 as follows:

B  
--The method according to the invention is to nitridise  
laser mirror facet of laser bars or laser chips during an etching  
process, such as milling with a gas comprising neutral nitrogen  
atoms or nitrogen ions in molecular and/or atomic form in a  
vacuum chamber. The facets of the laser bars were first cleaved  
in air, or some other ambient atmosphere. Introduction of a  
reactive gas like nitrogen in the etching process will certainly  
affect the crystal surface properties since it reacts with the  
crystal elements and creates a nitrided surface layer.--.